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## Patent Abstracts of Japan

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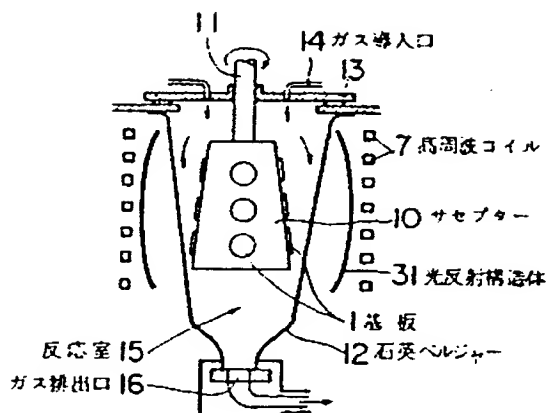
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TITLE : VAPOR GROWTH DEVICE



ABSTRACT : PURPOSE: To contrive to make film thickness of crystal growth layer uniform and to improve product yield, by arranging an approximately pyramidal susceptor in a bell-jar having outer peripheral length lessening from the top toward the bottom and setting a light reflecting structure of spherical surface of polygon at the outer peripheral part.

CONSTITUTION: An approximately pyramidal susceptor 10 having the top part opposing to the side of a gas inlet 14 is set in a bell-jar 12 equipped with the gas inlet 14 and a gas outlet 16 in the vertical direction, bases 1 are supported and a reaction gas is introduced to a reaction chamber 15. The gas is heated by a high-frequency coil 7 set at the outer peripheral part and a crystal layer is grown in vapor by chemical reaction on the bases 1. In the vapor growth device of a barrel type having the constitution, the reaction chamber 15 consists of the bell-jar 12 in the form wherein the outer peripheral length is gradually lessened from the top toward the bottom, and the reaction gas is made uniform. Further, a light reflecting structure 31 having a reflecting face made of spherical surface of polygon is set at the position opposing to the bases 1 at the outer peripheral part of the bell-jar and radiation heat is efficiently sent to the surface of the bases 1. Temperature gradient of the bases 1 at both sides is corrected and bending and crystallographic slippage are prevented.

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